

--43 The vacuum plasma processor of claim 40 wherein the power supply arrangement is arranged for supplying the reference voltage to the non-magnetic metal arrangement.

--44 The vacuum plasma processor of claim 40 wherein the power supply arrangement is arranged for supplying an RF energization voltage to the semiconductor member.--

Please cancel the following claims:

Claims 33-39 are canceled, without prejudice, and with the right to file a divisional application thereon.